

Title (en)  
MICROSTRUCTURE AND MANUFACTURING METHOD THEREOF

Title (de)  
MIKROSTRUKTUR UND HERSTELLUNGSVERFAHREN DAFÜR

Title (fr)  
MICROSTRUCTURE ET SON PROCÉDÉ DE FABRICATION

Publication  
**EP 2270262 A4 20120201 (EN)**

Application  
**EP 09738835 A 20090428**

Priority  
• JP 2009058381 W 20090428  
• JP 2008117264 A 20080428

Abstract (en)  
[origin: EP2270262A1] Disclosed is a structure that has a thickness of 100  $\mu\text{m}$  or greater and has regular micropores. A microstructure includes an aluminum or aluminum alloy oxide film which has cylindrical micropores extending from a bottom surface to a top surface of the microstructure. The micropores are arrayed at the bottom surface so as to have a degree of ordering as defined by general formula (1) of at least 70%, the center-to-center distance between neighboring micropores is from 300 to 600 nm and the axial length of the micropores is at least 100  $\mu\text{m}$ .

IPC 8 full level  
**C25D 11/04** (2006.01)

CPC (source: EP US)  
**C25D 11/024** (2013.01 - EP US); **C25D 11/045** (2013.01 - EP US)

Citation (search report)  
• [XPLY] EP 1976007 A2 20081001 - FUJIFILM CORP [JP]  
• [XY] EP 1715085 A2 20061025 - FUJI PHOTO FILM CO LTD [JP]  
• [XY] EP 1884578 A1 20080206 - MAX PLANCK GESELLSCHAFT [DE]  
• [IY] US 2008057293 A1 20080306 - HATANAKA YUSUKE [JP], et al  
• See references of WO 2009133898A1

Designated contracting state (EPC)  
AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO SE SI SK TR

DOCDB simple family (publication)  
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DOCDB simple family (application)  
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